

Applicant : Imad Mahawili, Ph.D
Serial No. : 09/488,309
Page : 6

69. (New)

The reactor according to Claim 68, wherein said means for ionizing the gas comprises a plasma generator.

70. (New)

The reactor according to Claim 69, further comprising a heater assembly for heating the substrate in said processing chamber, said heater assembly supporting said substrate in said processing chamber.

71. (New)

The reactor according to Claim 70, wherein said heater assembly is configured for rotatably supporting the substrate in said processing chamber.

REMARKS

An early and favorable action on the merits is respectfully solicited.

Respectfully submitted,

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By: Van Dyke, Gardner, Linn & Burkhart, LLP

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